

Speaker Profile

 <p>Contact Details</p> <p>Organization Name: Korea Institute of Machinery and Materials</p> <p>Address: 171 Jang-dong, YuSung-ku, DaeJeon</p> <p>Phone: +82-42-868-7145</p> <p>Fax: +82-42-868-7721</p> <p>Email: jjlee@kimm.re.kr</p> <p>Website: www.kimm.re.kr</p>	<p>Name : JaeJong Lee</p> <p>Title : Key Issues of the UV-Nanoimprint Equipment for Sub-50nm Half-pitch Patterns</p> <p>Institute : Korea Institute of Machinery and Materials</p> <p>JaeJong Lee received the BS in precision machine engineering from Chonbuk National University in 1985, a MS in production engineering from Korea Advanced Institute of Science & Technology(KAIST) in Seoul in 1987, and Ph.D in Mechanical Engineering from Korea Advanced Institute of Science & Technology(KAIST) in DaeJeon in 1998. Since 1987 he has been working at the Korea Institute of Machinery and Materials(KIMM) in DaeJeon, Korea.</p> <p>He is currently the Team Leader of the Nanomechanism Team of KIMM. He has been involved in developing nanoimprinting lithography equipment for large size wafer in CNMM which is one of the 21st century frontier program supported by Ministry of Science and Technology in Korea for exploring an emerging cutting-edge technology. He has research interests in the thermal and UV nanoimprinting lithography process and equipment technologies, and also SEM and e-beam lithography process and equipment technology for 3D functional device and sensors.</p>
--	--